

PG2000D Double-sided Semi-automatic Probe Station

PEGASUS PG2000D is developed for testing components such as DIODE, MOSFET and IGBT wafers. PEGASUS PG2000D is a probe station with a double-sided, four-wire probe structure. The structure eliminates impedance problem on the probe platform and minimizes the effect on test results. It makes the component under test to be closer to the engineering design requirements.



Features

- Robust housing and compact size
- Supports Windows system, English software interface, real-time mapping graph display
- Easy-to-use control console and joystick
- High-precision drive motor provides stable and quiet operating environment
- Easy-to-maintain modular electronic control mechanism
- Double-sided probe structure to improve test circuit impedance. Test current up to 30A
- Applicable to 3" ~ 8" wafers
- Customized designs available
- Standard TTL and RS232 communication interface for variety of testers
- Excellent probing speed and probe marks

PG2000D Double-sided Semi-automatic Probe Station

Specifications

XY axis

- Architecture: High-precision circulating ball screw
- Travel: 210mm × 210mm
- Resolution: 0.5 μm
- Accuracy: $\cong \pm 7 \mu\text{m}$ (203mm)
- Repeatability: $\pm 4 \mu\text{m}$ (203mm)

Probe arm

- Travel: 10mm
- Resolution: 1 μm
- Accuracy: $\cong \pm 2 \mu\text{m}$
- Repeatability: $\pm 4 \mu\text{m}$

Chuck plate

- Material: High insulation artificial stone plate
- Wafer size: 3" / 4" / 5" / 6" / 8"
- Adjustable angle: $\pm 10^\circ$
- Resolution: 0.001°

Microscope

- Eyepiece: 20X
- Objective: 1X~4.5X
- Magnification: 20X~90X

Dimension

- 90 (D) x 70 (W) x 173 (H) cm
(Excludes microscope, signal tower and monitor)

Test time

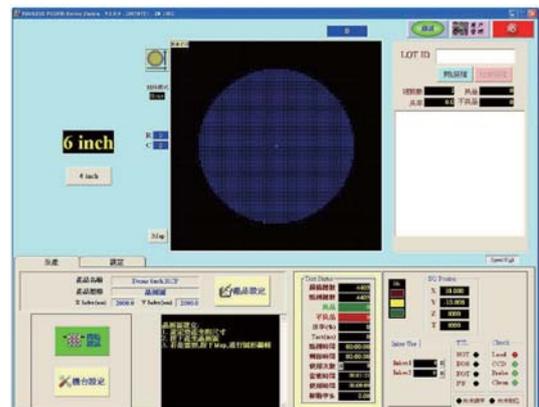
Test Time (ms)		Index Step(μm)			
		300	500	1000	2000
Chuck Lift (μm)	300	50	58	72	91
	500	62	69	83	102
	800	77	84	98	118
	1000	87	94	108	127

Weight

- 250 KG

Options

- Various types of microscopes
- CCD Camera



English software interface
Real-time mapping graph